

RECEIVED

OCT 2 1 2004

NEC 2370-US

Technology Center 260@415001228

1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Kazuhiko Hayashi

Serial No. 09/853,622

Group Art Unit 2652

Filed May 14, 2001

Examiner C. Renner

For

MAGNETORESISTIVE EFFECT SENSOR, METHOD FOR
MANUFACTURING A MAGNETORESISTIVE EFFECT SENSOR,
MAGNETORESISTIVE DETECTION SYSTEM, AND
MAGNETORESISTIVE RECORDING SYSTEM

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Please enter CAP/1-18-05

DECLARATION UNDER 37 C.F.R. §1.132 OF KAZUHIKO HAYASHI

Sir:

KAZUHIKO HAYASHI declares as follows:

- 1. I am co-inventor of U.S. Patent No. 6,490,139 to Hayashi et al. ("Hayashi '139").
- 2. With respect to Hayashi '139, I am the sole inventor of any relationship disclosed therein between the smoothness of the lower shield layer and the materials, as disclosed therein, used to form the lower shield layer.
- 3. I am the sole inventor of the invention disclosed in the above captioned application, and in particular of achieving a reduction in the surface roughness of a